

What is claimed is:

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5 1. A semiconductor factory automation (FA) system, comprising:  
at least one processor for driving a program process and  
providing processor state information, wherein the processor state  
information includes an availability of a central processing unit,  
an availability of a disk and a state of the program process related  
to said processor;

10 a storing means for storing the processor state information in  
a real time;

a monitoring means for retrieving the processor state  
information in said storing means to monitor said processor; and

15 a displaying means for displaying the processor state  
information retrieved.

20 2. The semiconductor FA system as recited in claim 1, wherein  
said displaying means includes:

a first display space for displaying the availability of the  
central processing unit related to said processor; and

a second display space for displaying the availability of the  
disk related to said processor.

25 3. The semiconductor FA system as recited in claim 2, wherein  
said displaying means further includes:

a first light emitting device for emitting a light when the disk  
has failed;

a second light emitting device for emitting the light when the

program process is in a down state; and

a third light emitting device for emitting the light when a communication between said monitoring means and said processor is disconnected.

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4. The semiconductor FA system as recited in claim 3, wherein said displaying means further includes:

a third display space for displaying identification information of the program process of the down state.

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5. The semiconductor FA system as recited in claim 4, wherein said processor is coupled to Ethernet™ supplied by Xerox Corporation.

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6. The semiconductor FA system as recited in claim 5, wherein said at least one processor includes a first processor and a second processor.

7. The semiconductor FA system as recited in claim 6, further comprising:

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a semiconductor processing means coupled to said first processor for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers;

a stocking means coupled to said second processor for stocking the semiconductor wafer cassette; and

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a transportation means for transporting the semiconductor wafer cassette from said semiconductor processing means to said stocking means or from said stocking means to said semiconductor processing

means.

8. A method for monitoring at least one server in a semiconductor factory automation (FA) system, comprising the steps of:

5 a) providing server state information from at least one server to a real-time database, wherein the server state information includes an availability of a central processing unit, an availability of a disk and a state of a program process related to the server;

10 b) storing the server state information in the real-time database;

c) retrieving the server state information to monitor the server; and

d) displaying the server state information retrieved.

15 9. The method as recited in claim 8, wherein said step d) includes the steps of:

d1) displaying the availability of the central processing unit related to the server; and

20 d2) displaying the availability of the disk related to the server.

10. The method as recited in claim 9, wherein said step d) further includes the steps of:

25 d3) emitting a light when the disk has failed; and

d4) emitting the light when the program process is in a down state.

11. The method as recited in claim 10, wherein said step d) further includes the step of:

d5) displaying identification information of the program  
5 process of the down state.

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